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Att. Docket No. 10191/1629

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. Serial No. : 09/720,761 Confirmation No. 5642  
Title : METHOD OF PLASMA  
ETCHING OF SILICON  
Applicant(s) : Franz LAERMER et al.  
Filed : March 26, 2001  
TC/A.U. : 1765  
Examiner : Kin Chan Chen  
Docket No. : 10191/1629  
Customer No. : 26646

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Thereby certify that this correspondence is being deposited with the  
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on \_\_\_\_\_

Date:

3/29/2004

Signature:

AARON C. DEDITCH  
(33,865)

TRANSMITTAL AND PETITION TO EXTEND

SIR:

Transmitted herewith for filing in the above-identified patent application is an  
Amendment.

This is also a Petition Under 37 C.F.R. § 1.136(a) to extend the three-month response  
date by one month from March 1, 2004 to April 1, 2004.

The Commissioner is authorized to charge the appropriate fee, which is believed to be  
\$110.00 for the one-month extension, to Deposit Account No. 11-0600, and is also  
authorized, as appropriate and/or necessary, to charge any additional fees (including any other  
Rule 136(a) extension fees) or credit any overpayment to Deposit Account No. 11-0600. A  
duplicate copy of this transmittal letter is enclosed for this purpose.

Respectfully submitted,

Dated:

3/29/2004

By:

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